

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **IRINO, Kiyoshi**

Serial No.: **09/428,052**

Filed: **October 27, 1999**



Group Art Unit: **2815**

Examiner: **DIAZ, Jose R.**

Conformation No.: **4139**

For: **METHOD OF FABRICATING A SEMICONDUCTOR DEVICE CONTAINING NITROGEN IN A GATE OXIDE FILM**

PETITION FOR EXTENSION OF TIME

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Date: December 8, 2003

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated August 7, 2003, for one month from November 7, 2003 to December 8, 2003 (December 7, 2003 was a Sunday).

Attached please find a check in the amount of \$110.00 to cover the cost of the extension. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 50-2866. This paper is filed in triplicate.

Respectfully submitted,  
WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP

*John Kong*  
JOHN KONG  
Reg. No. 40,054 for  
*Stephen G. Adrian*  
Stephen G. Adrian  
Reg. No. 32,878

SGA/arf

Atty. Docket No. **970901A**  
1250 Connecticut Avenue, N.W.  
Suite 700  
Washington, D.C. 20036  
(202) 822-1100



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